

ABSTRACT OF THE DISCLOSURE

A sample manufacturing device comprises a sample stage to which an original sample is fixed, a focused ion beam irradiation system for irradiating a focused ion beam from a vertical direction to a specified place on the original sample, and a side entry stage, arranged diagonally above the sample stage, for inserting a sample stage for specified observation in a diagonal direction with respect to the vertical direction, and supporting the inserted sample holder for observation so as to be capable of movement in the diagonal direction. A test piece taken out from a specified place of the original sample is fixed to a tip section of the sample holder for specified observation supported on the side entry stage.